

MTJ Magnetization Switching Mechanisms for IoT Applications

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ABSTRACT

Different magnetization mechanisms, structures, and electrical properties of MTJ-based MRAM are described in the context of IoT applications. MTJ-based MRAM provides non-volatility (high retention time), low power, and high speed. This memory has a broad variety of applications. One important example is IoT. A comparative study of the magnetization mechanisms provides insight into which MTJ structures and magnetization mechanisms best support different IoT applications.

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1 INTRODUCTION

The internet of things (IoT) or the internet of everything has become a primary vehicle for connecting multiple nodes throughout a large network. Each of these nodes may include a small processing unit to collect information, communicate with other nodes, and respond to stimuli. Integrated memory will be needed in all of these IoT applications. Form factor, initialization time, power dissipation, read/write speed, and cost are primary design criteria. Magnetic tunnel junction (MTJ)-based magnetic random access memory (MRAM) is a potentially important

solution for IoT applications. MTJ-based MRAM provides a nonvolatile memory able to operate at low latency, low leakage current, and high density. These capabilities support MRAM becoming the universal memory as compared to other nonvolatile memories such as e-Flash, phase change RAM, or resistive RAM [1].

This discussion is outlined as follows. In section 2, the physical behavior and parameters affecting MTJ device performance are described. Different forms of magnetization operation are also discussed in section 2. In section 3, the primary magnetization mechanisms for different structures are characterized. A comparative study of the different magnetization mechanisms described in section 3 is provided in section 4, emphasizing scaling, power dissipation, and circuit speed. A discussion of the effects of thermal variations on the different magnetization mechanisms for IoT applications is provided in section 5. Appropriate magnetization mechanisms applicable for different IoT applications are also described in sections 4 and 5. A summary is provided in the conclusions section.

2 MTJ STRUCTURES FOR MRAM

Tunneling magnetoresistance (TMR) was discovered in 1975 by Julliere [2] within a structure called a magnetic tunnel junction. It was not until the mid-1990s when fabrication of reliable MTJs became possible with the development of certain growth techniques and lithographic processes [3,4] did MTJ become a commercially interesting technology. The basic MTJ structure is composed of two ferromagnetic (FM) materials separated by a nonmagnetic insulator, where the conductivity of the structure is determined by the angle between the magnetization direction of the two ferromagnetic layers. Maximum conductivity is achieved when both magnetization directions are in parallel, and minimum conductivity when anti-parallel (AP). Slonczewski describes the conductance of the structure as a function of θ , the angle between the magnetization direction in the two FM materials, as [5]

$$G(\theta) = G_o(1 + P^2 \cos \theta), \quad (1)$$

where P is the spin polarization of the ferromagnetic/barrier couple, and G_o is the conductance of the AP configuration. A primary parameter characterizing the quality of an MTJ is the TMR,

$$TMR = \frac{G_P - G_{AP}}{G_{AP}}, \quad (2)$$

where G_P and G_{AP} are, respectively, the conductivity of the parallel ($\theta = 0^\circ$) and anti-parallel ($\theta = 180^\circ$) configurations.

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The ability to control the MTJ conductivity by the difference in magnetization angle θ is the key concept in using an MTJ as a building block for magnetic memory (such as MRAM). The FM layer is pinned while controlling the direction of magnetization of the other FM free layer (the storage layer). The FM layers are fabricated as uniaxial anisotropy layers (with a preferable single magnetization axis). The magnetization dynamics in the free layer are derived from the Landau–Lifshitz–Gilbert (LLG) equation [6,7], as

$$\frac{\partial \vec{M}}{\partial t} = -\gamma \vec{M} \times \vec{H}_{eff} + \alpha \vec{M} \times \frac{\partial \vec{M}}{\partial t} - \gamma \sum \vec{\tau}_i, \quad (3)$$

where $\vec{M}$ is the free layer magnetization, t is the time variable, $\vec{H}_{eff}$ is the effective magnetic field applied to the free layer, γ is the gyromagnetic ratio, α is the Gilbert damping factor, and $\vec{\tau}_i$ is the applied torque due to other switching mechanisms such as spin transfer torque (STT) or spin orbital torque (SOT). The effective magnetic field applied to the free layer $\vec{H}_{eff}$ is [1]

$$\vec{H}_{eff} = \vec{H}_{UA} - \vec{H}_{dem} + \vec{H}_c + \vec{H}_{APP} - \vec{H}_{VCMA} + \vec{H}_{th}, \quad (4)$$

where $\vec{H}_{UA}$ is the uniaxial anisotropy field, $\vec{H}_{dem}$ is the demagnetization field, $\vec{H}_c$ is the coupling field due to the other FM layer, $\vec{H}_{APP}$ is the applied magnetic field, $\vec{H}_{VCMA}$ is due to the voltage controlled magnetic anisotropy (VCMA), and $\vec{H}_{th}$ is the stochastic magnetic field due to thermal variations.

MTJ structures are based on uniaxial anisotropy which means the magnetization direction prefers stability over a single axis (easy axis), ensuring the free layer is either in the parallel state or antiparallel state with respect to the pinned reference layer. Switching is controlled by applying a perturbing field by injecting current, applying an external magnetic field, or some other means. Uniaxial magnetic anisotropy (MA) is achieved by different MTJ structures to obtain either an in-plane MTJ (IMTJ) or perpendicular MTJ (PMTJ). Shape magnetic anisotropy is the main source for in-plane magnetic anisotropy where an elliptical MTJ is preferred as the magnetization tends to be directed along the long axis. A circular shape is preferred in the case of a perpendicular MTJ (PMTJ). Perpendicular magnetic anisotropy (PMA) in a PMTJ is due to two reasons, magneto-crystalline anisotropy of the crystalline lattice of the FM layer or by an interfacial magnetic anisotropy due to coupling at the interface between the FM layer and a neighboring layer (such as Co/Pt and Co/Pd [9]).

The pinned reference FM layer is achieved through the exchange bias effect by attaching an FM layer to an antiferromagnetic material. A synthetic antiferromagnetic structure (SAF) is preferred to achieve the pinned FM layer by using two antiparallel FM layers separated by a nonmagnetic (NM) metallic layer, reducing any stray fields affecting the free layer, as shown in Figure 1.

Numerous developments in MTJ structures have been achieved to enhance the TMR and other performance metrics. Different configurations used to switch the MTJ magnetization are discussed in section 3. Switching by applying a magnetic field or injecting a current through the MTJ structure is described. Other forms of assistive switching, such as thermally assisted switching, are also discussed.

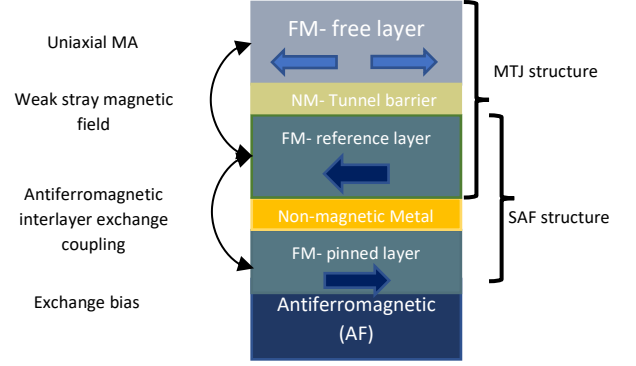


Figure 1. Stacking structure of IMTJ with SAF

3 MTJ-BASED MRAM MAGNETIZATION MECHANISMS

Several magnetization mechanisms of MTJ-based MRAM have been developed. Controlling the magnetization direction of the free layer can be achieved by applying an external magnetic field (induced by current passing through a nearby wire) [10], injecting current through an MTJ structure to cause thermal perturbations to affect device magnetization properties (thermally assisted) [11], injecting greater current to induce spin transfer torque to the magnetization layer [12], or by adding an additional perpendicular magnetization layer within an IMTJ to enhance STT performance to reduce the write current [13]. Recently developed magnetization mechanisms in MRAM are also discussed in this section.

3.1 Field-Induced Magnetic Switching MRAM (FIMS-MRAM)

The magnetic field required to switch an MTJ is governed by the relationship, $\mu_0 H_{write} = 2K/M_s$, where K is a constant characterizing the magnetic anisotropy of the MTJ. The Stoner-Wohlfarth MRAM (ST-MRAM) was the first demonstrated MTJ-based MRAM, based on Stoner-Wohlfarth (SW) switching, as shown in Figure 2 [2]. Two orthogonal magnetic fields - one along the easy axis - are applied to an MTJ structure. The total field applied over the x and y axis, respectively, H_x and H_y , based on (5), sets the lower limit of the write field,

$$H_x^{2/3} + H_y^{2/3} = \left(\frac{2K_u}{M_s} \right)^{2/3}, \quad (5)$$

where K_u is the magnetic anisotropy constant and M_s is the saturated magnetization. The upper limit of the switching operation is bounded by the MTJ shape, where the easy axis field is lower than the anisotropy field, $H_K = 2K_u/M_s$.

An improved field written mechanism has been achieved by Savtchenko [3], where two orthogonal fields are oriented at an angle of 45° to the MTJ easy axis. The write operation is performed in a toggle form to maintain full magnetization operation, hence called “Toggle MRAM.” The spin flip flop field H_{spin_flop} is

$$\mu_0 M_s H_{spin_flop} = 2 \sqrt{K_{eff} \left(\frac{A}{t} + K_{eff} \right)}, \quad (6)$$

assuming the two FM layers are identical with a thickness t (a symmetric MTJ). K_{eff} is the effective anisotropy, and A is the interfacial coupling through the spacer (the tunnel barrier).

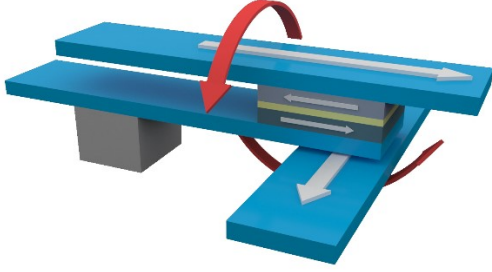


Figure 2. IMTJ writing using FIMS

3.2 Spin Transfer Torque MRAM (STT-MRAM)

In STT-MRAM, switching the magnetization of the free layer is achieved by passing a polarized electric current through an MTJ structure, where the polarized moving electrons exert a torque on the magnetic storage layer. When a normal unpolarized current passes through an FM layer, the current becomes polarized by the FM layer with a spin polarization factor [5]. Based on whether the current direction is into or out of the MTJ structure (the pinned layer), respectively, an antiparallel or parallel configuration is achieved, as shown in Figure 3.

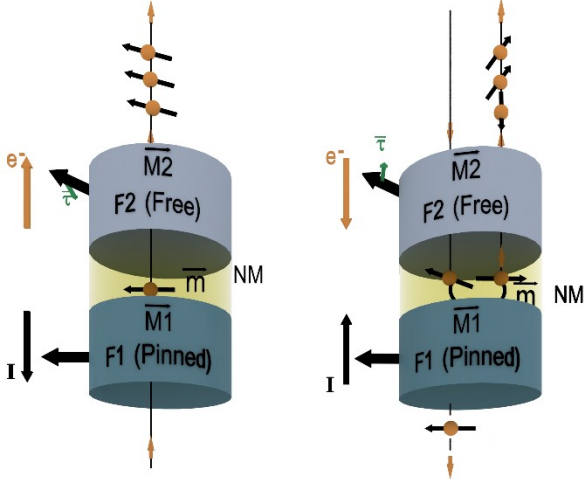


Figure 3. IMTJ writing using STT

The switching current should be greater than a critical magnitude, where the level depends upon the device dimensions and materials. For an IMTJ, the critical current density J_{co} to switch the FM layer is described by (8). The critical current is affected by thermal variations and depends upon the width of the current pulse. The critical current $J_c(t)$ is described by (7),

$$J_c(t) = J_{co} \left[1 - \frac{K_B T}{K_u V_{FL}} \ln \left(\frac{t}{\tau_0} \right) \right], \quad (7)$$

$$J_{co} = \frac{2e\alpha\mu_0 M_s t_{FL} (H_{K1} + \frac{M_s}{2})}{\hbar \eta}, \quad (8)$$

where e is the electron charge, μ_0 is the permeability of free space, t_{FL} is the thickness of the FM, H_{K1} is the in-plane magnetic anisotropy field, $\hbar$ is the reduced plank constant, η is the spin transfer efficiency, t is the pulse width, K_B is the Boltzmann constant, T is the temperature, K_u is the uniaxial magnetic anisotropy constant, V_{FL} is the volume of the FM layer, and $\tau_0 \sim 1$ is the inverse of the frequency factor or the attempt frequency of the thermal reaction.

For an IMTJ, the magnetization configuration does not efficiently support both thermal stability and writability [8]. Other configurations to reduce the critical current in an IMTJ are

- Dual MTJ: where the storage FM layer is sandwiched between two pinned FM layers, hence the current passing through the structure exerts a larger torque (2x), reducing the critical current to switch the layer [16].
- Perpendicular polarizer: where a perpendicular polarizer is stacked within an MTJ [17], enhancing the precessional switching. The storage layer acquires an out-of-plane component due to the added magnetic precessional movement.
- Reduced demagnetized field: where either volume or interfacial perpendicular magnetic anisotropy is added – by changing the barrier and FM materials – decreasing the demagnetizing field effect, thereby reducing the critical current [18].

MTJ structures that exhibit magnetic anisotropy normal to the surface are faster, dissipate less power, and are higher density than an IMTJ due to a lower critical current and the circular shape of the magnetic cell. A PMTJ-based MRAM is therefore more appropriate for IoT applications than an IMTJ. The critical current density J_{co} for a PMTJ is described by (9) where $H_{K\perp}$ is the perpendicular-to-plane magnetic anisotropy,

$$J_{co} = \frac{2e\alpha\mu_0 M_s t_{FL} (H_{K\perp} - M_s)}{\hbar \eta}. \quad (9)$$

A PMTJ suffers from a higher Gilbert damping factor α than an IMTJ. In addition, it is difficult to fabricate the crystalline PMTJ structure to produce perpendicular magnetic anisotropy. The critical procedures of annealing and oxidation are required to grow a PMTJ. That leads to a preferential choice between IMTJ and PMTJ based on the manufacturing difficulty. A comparative study between IMTJ and PMTJ in terms of IoT applications is provided in section 4.

3.3 Thermally assisted MRAM (TA-MRAM)

In TA-MRAM, thermal variations are induced by passing current through an MTJ and/or using a high thermal conductivity material. The magnetic anisotropy constant is lower at higher temperatures which affects the magnetic field writing to the storage layer. Accordingly, a thermal assist mechanism is integrated within the FIMS-MRAM structure, achieving higher performance [19].

The same concept can be applied to an STT-MRAM, where the same current line is used for heating and switching the cell. The write operation is composed of multiple stages. The first stage

heats the cell by passing a current for a specific duration. A lower level of current is applied for a different duration to switch the state. The cell is left to cool, storing the written state [20].

4 COMPARATIVE STUDY

A PMA-based STT-MRAM structure exhibits better performance, as listed in Table 1, due to a higher density and reduced power [21]. Research is on-going for determining the optimum device characteristics to provide acceptable performance as a replacement memory technology. Research on different structures, materials, and mechanisms suggests that a PMTJ-based MRAM is more applicable for those IoT applications that require higher operating speed.

Table 1. Advantages and disadvantages of different MTJ structures

Technique	Advantages	Disadvantages
IMA	• Controlled retention time	• Density, power consumption
Interfacial PMA	• Higher density • Optimizing I_c and α	• Low retention time
Crystalline PMA	• Higher density	• Larger α • Low retention time
SAF pinned layer	• Symmetric MTJ switching	• Increases height of MTJ stack
Dual MgO/Free layer interface	• Enhance interfacial PMA • Reduces α	• Increases MTJ resistance (R_{MTJ})
Dual tunnel barrier with dual PL	• Reduces I_c , α	• Increases R_{MTJ} • Increases height of MTJ stack
Tilted magnetic anisotropy(MA)	• Reduces I_c	• Reduces TMR ratio • Difficult to fabricate
Orthogonal pinned layer	• Reduces I_c without affecting TMR ratio	• Increases height of MTJ stack • Difficult to fabricate

A comparison of magnetization mechanisms for MTJ-based MRAM is summarized in Table 2 [22,1]. A FIMS-MRAM is based on an IMTJ, requiring large cells (which suffers from scaling and bit selectivity due to stray field disturbance from the writing magnetic field from neighboring cells). FIMS consumes large power (due to the large write current to induce the write magnetic field) but exhibits long retention times and thermal stability.

Toggle based MRAM solves the selectivity problem but can place the memory bit in an undefined state – requiring the read operation to be performed before the write operation. A toggle MRAM is predicted to not be highly scalable below 90 nm [1]. FIMS is a robust technology, exhibiting high reliability, endurance, and resistance to radiation, making it a good candidate for automotive, sensor-based weather forecasting, and IoT applications [8,25].

Table 2. Performance of different magnetization mechanisms

	Scalability	Endurance	Write time	Write current
FIMS	Poor	10^{16}	>10 ns	~ 10 mA
Toggle	Good	10^{15}	>30 ns	>30 mA
TAS	Good	10^{12}	>20 ns	~ 1 mA
STT	Very good	10^{16}	<5 ns	~100 μ A
TAS+STT	Best	10^{12}	<8 ns	~100 μ A

The advantages and disadvantages of STT-MRAM are illustrated in Figure 4 [24], where the reliability is improved by optimizing the read/write currents, utilizing novel FM and barrier materials, or applying different magnetization mechanisms such as VCMA or SOT. Spin orbit torque MRAM (SOT-MRAM) shows promising potential due to the separate read and write paths, supporting symmetric switching.

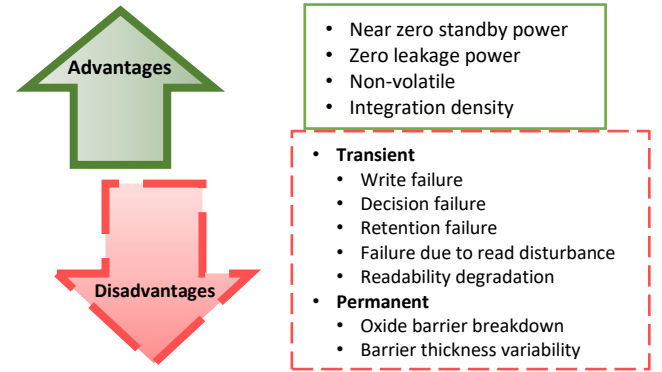


Figure 4. Advantages and reliability challenges of STT-MRAM

The thermally assisted switching (TAS) mechanism requires less writing power and is higher speed than FIMS, although difficult to scale. STT-based mechanisms exhibit better performance for both IMTJ and PMTJ [1,21-24]. TAS-based MRAM suffers from the same problems as FIMS. Merging TAS with STT-MRAM exhibits better scalability and performance as compared to FIMS, TAS, and STT-MRAM [22,1]. TAS+STT-MRAM is a good candidate for IoT applications which require high speed while dissipating low power.

5 MTJ-BASED MRAM FOR DIFFERENT TEMPERATURES

The operation of an MTJ-based MRAM as a nonvolatile memory is composed of three states. The write state with one magnetization mechanism, the retention state, describing how long the memory can maintain the written information, and the read state. The key objective in MTJ-based MRAM is to maintain low read/write/idle power consumption, high retention time, a wide operating temperature range, and low read and write delays. Each of these objectives are affected by the thermal stability factor Δ , as expressed in (10),

Figure 6. MRAM development trend

Toggle MRAM is a good candidate for those IoT applications requiring long periods of standby current as this technology is non-volatile with fast write times. TAS with STT-MRAM within a PMTJ structure is a better choice for ultra-low power, battery operated IoT nodes, as this application requires zero standby energy with a fast power-up time.

6 CONCLUSIONS

MTJ-based MRAM is an effective candidate technology for the specialized memory needed in IoT applications. PMTJ structures exhibit higher density and lower power than IMTJ due to the circular shape and perpendicular interfacial or magnetocrystalline anisotropy. STT-MRAM assisted with TAS provides enhanced speed and power as compared to FIMS, toggle, TAS, and STT-MRAM. The ability to maintain a ten year retention time operating at extremely low energy makes MRAM highly appropriate for IoT applications, particularly for sensor nodes located in harsh environmental conditions.

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